



Attorney's Docket No.: 77/213002 / US3521/3522

6/Churisa
5-2-01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Ohtani, et al. Art Unit : 2815
Serial No. : 09/455,991 Examiner : Jose R. Diaz
Filed : December 6, 1999
Title : SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING
THE SAME

Commissioner for Patents
Washington, D.C. 20231

RESPONSE

In response to the action mailed November 21, 2000, please
amend the application as follows:

In the claims:

Please amend claims 6-12 as follows:

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TC 2800 MAIL ROOM

6. (Amended) A method of manufacturing a semiconductor
device, said method comprising:

forming an amorphous semiconductor film on an
insulating surface;

A1
sub B1

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this
correspondence is being deposited with the
United States Postal Service as first class mail
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April 23, 2001

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Nancy Grant

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